

Trip Report on IEDM 2018

Teo, K.H.

TR2018-193 March 13, 2019

Abstract

Koon Hoo Teo attended the International Electron Device Meeting (IEDM) 2018 in San Francisco from Dec 1 to 5, 2018. The meeting has attracted many attendees, more than 3,000, as this is considered as the gold standard for semiconductor devices research. As expected, this meeting is well attended by both academia and Industries. Areas of interest include Quantum Computing (6 papers), Negative Capacitance and Ferroelectric (17 papers) and GaN (9 Papers) and many others.

Mitsubishi Electric Research Laboratories

This work may not be copied or reproduced in whole or in part for any commercial purpose. Permission to copy in whole or in part without payment of fee is granted for nonprofit educational and research purposes provided that all such whole or partial copies include the following: a notice that such copying is by permission of Mitsubishi Electric Research Laboratories, Inc.; an acknowledgment of the authors and individual contributions to the work; and all applicable portions of the copyright notice. Copying, reproduction, or republishing for any other purpose shall require a license with payment of fee to Mitsubishi Electric Research Laboratories, Inc. All rights reserved.

Trip Report on IEDM 2018

Koon Hoo Teo, Version 1.0, January 3, 2019

Summary

Koon Hoo Teo attended the International Electron Device Meeting (IEDM) 2018 in San Francisco from Dec 1 to 5, 2018. The meeting has attracted many attendees, more than 3,000, as this is considered as the gold standard for semiconductor devices research. As expected, this meeting is well attended by both academia and Industries. Areas of interest include Quantum Computing (6 papers), Negative Capacitance and Ferroelectric (17 papers) and GaN (9 Papers) and many others.

Wide Bandgap Devices— Wide bandgap (WBG) devices offer potential cost saving and technical merits. Converters designed with WBG devices triggers innovation at all levels, which includes system design and circuit architecture. Question discussed include whether SiC or GaN could perform better than what silicon can possibly attained and the challenges to the widespread adoption of these technologies. Barriers to adoption of these technologies include cost, device design and fabrication, reliability and system integration. Presenters include companies such as Infineon, Transphorm and ABB. Development in GaN includes

1. Breakdown fields of 2.8-3.5 MV/cm in GaN on GaN p-n Junction diodes with double side depleted termination
2. Atomically flat AlGaIn spacer layers were use to reduce the 2DEG densities and improve carrier mobility while maintaining the low access resistance. This lower electric-field concentration at the edge of gate electrodes enables high voltage operation. Furthermore, a diamond heat spreader decreases the thermal resistance to further improve the output power density.
3. Exposure to hard switching transitions may lead to an increase in dynamic Ron. This effect is ascribed to the presence of hot electrons and verified through electroluminescence measurements.

Details

The following GaN related presentations were attended (see <https://ieee-iedm.org>):

GaN HEMTs for 5G Base Station Applications

Shigeru Nakajima

Semiconductor Innovation Business Unit, Sumitomo Electric Industries, Ltd., Yokohama, Japan, email: snakajm@sei.co.jp

Suppressed Hole-Induced Degradation in E-mode GaN MIS-FETs with Crystalline GaOxN1-x Channel

Mengyuan Hua¹, Xiangbin Cai², Song Yang¹, Zhaofu Zhang¹, Zheyang Zheng¹, Jin Wei¹, Ning Wang², and Kevin J. Chen¹

¹Department of ECE, ²Department of Physics, The Hong Kong University of Science and Technology, Hong Kong, China

email: mhua@connect.ust.hk

Recent advancement of GaN HEMT with

InAlGaN barrier layer and future prospects of AlN-based electron devices

J. Kotani^{1,2}, A. Yamada^{1,2}, T. Ohki^{1,2}, Y. Minoura^{1,2}, S. Ozaki^{1,2}, N. Okamoto^{1,2}, K. Makiyama^{1,2}, and N. Nakamura^{1,2}

¹ Fujitsu Ltd., ²Fujitsu Laboratories Ltd., 10-1 Morinosato-Wakamiya, Atsugi-shi, Kanagawa, Japan

email: kotani.junji-01@jp.fujitsu.com

Power GaN HEMT degradation: from time-dependent breakdown to hot-electron effects

M. Meneghini¹, A. Barbato¹, M. Borga¹, C. De Santi¹, M. Barbato¹, S. Stoffels², M. Zhao², N. Posthuma², S. Decoutere²,

O. Haeberlen³, T. Detzel³, G. Meneghesso¹, E. Zanoni¹

¹Univ. of Padova, Dept. of Information Engineering, via Gradenigo 6/B 35131 Padova (Italy),

email: matteo.meneghini@unipd.it ²Zimec, Kapeldreef 75, 3001 Heverlee (Belgium) ³Infineon, Siemensstraße 2, 9500 Villach, Austria

GaN devices for automotive application and their challenges in adoption

Tetsu Kachi

Institute of Materials and Systems for Sustainability, Nagoya University,

Nagoya, 464-8601, Japan, email: kachi@imass.nagoya-u.ac.jp

Barriers to the Adoption of Wide-Bandgap

Semiconductors for Power Electronics

I.C. Kizilyalli¹, E.P. Carlson², and D.W. Cunningham¹

¹Advanced Research Projects Agency-Energy, U.S. Department of Energy, Washington, DC,

email: Isik.Kizilyalli@hq.doe.gov

²Booz Allen Hamilton, Washington, DC